

# Robert J Lovelett

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/7864572/publications.pdf>

Version: 2024-02-01

11  
papers

192  
citations

1307594

7  
h-index

1474206

9  
g-index

11  
all docs

11  
docs citations

11  
times ranked

262  
citing authors

#	ARTICLE	IF	CITATIONS
1	Modeling the Effect of Amino Acids and Copper on Monoclonal Antibody Productivity and Glycosylation: A Modular Approach. <i>Biotechnology Journal</i> , 2021, 16, e2000261.	3.5	7
2	Dynamical Modeling of Optogenetic Circuits in Yeast for Metabolic Engineering Applications. <i>ACS Synthetic Biology</i> , 2021, 10, 219-227.	3.8	9
3	Some manifold learning considerations toward explicit model predictive control. <i>AIChE Journal</i> , 2020, 66, e16881.	3.6	8
4	Design and Characterization of Rapid Optogenetic Circuits for Dynamic Control in Yeast Metabolic Engineering. <i>ACS Synthetic Biology</i> , 2020, 9, 3254-3266.	3.8	34
5	Partial Observations and Conservation Laws: Gray-Box Modeling in Biotechnology and Optogenetics. <i>Industrial &amp; Engineering Chemistry Research</i> , 2020, 59, 2611-2620.	3.7	15
6	Overcoming Carrier Concentration Limits in Polycrystalline CdTe Thin Films with In Situ Doping. <i>Scientific Reports</i> , 2018, 8, 14519.	3.3	84
7	Hierarchical monitoring of industrial processes for fault detection, fault grade evaluation, and fault diagnosis. <i>AIChE Journal</i> , 2017, 63, 2781-2795.	3.6	22
8	A stochastic model of solid state thin film deposition: Application to chalcopyrite growth. <i>AIP Advances</i> , 2016, 6, 045015.	1.3	1
9	Growth of Cu(In, Ga)(S, Se) films: Unravelling the mysteries by in-situ X-ray imaging. , 2016, , .		3
10	Design and experimental implementation of an effective control system for thin film Cu(InGa)Se <sub>2</sub> production via rapid thermal processing. <i>Journal of Process Control</i> , 2016, 46, 24-33.	3.3	9
11	A stochastic model for Cu(InGa)(SeS) <sub>2</sub> absorber growth during selenization/sulfization. , 2015, , .		0